IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Makoto AKIZUKI et al.

Attn: APPLICATION BRANCH Serial No. [NEW]

Attorney Docket No. 2000-1897 Filed December 26, 2001

METHOD FOR FORMING GAS CLUSTER AND METHOD FOR FORMING THIN FILM (Rule 1.53(b) Continuation of Serial No. 09/799,681, Filed March 7, 2001)

CHANGE OF ADDRESS

Assistant Commissioner for Patents, Washington, D.C.

Sir:

Effective IMMEDIATELY, please note the following change of address

for the undersigned attorney of record:

WENDEROTH, LIND & PONACK, L.L.P. 2033 "K" Street N.W. Suite 800

Washington, D.C. 20006

Telephone: (202) 721-8200 Fax: (202) 721-8250

Respectfully submitted,

Makoto AKIZUKI et al.

By Matthew Jacob Registration No. 25,154

Attorney for Applicants

MJ/pjm Washington, D.C. 20006 Telephone (202) 721-8200 December 26, 2001